Layer-modulated synthesis of uniform tungsten disulfide nanosheet using gas-phase precursors.

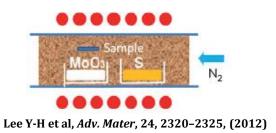
Jusang Park* Hyungjun Kim

School of Electrical and Electronics Engineering, Yonsei University, 262 Seongsanno, Seodaemun-gu, Seoul, Korea

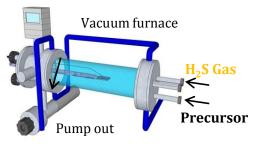
Growth of CVD WS₂

<Pre><Previous CVD method>

<Gas Phase CVD WS₂>



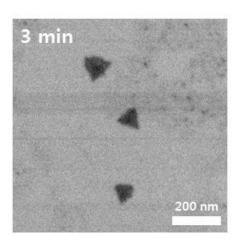
WCl₆

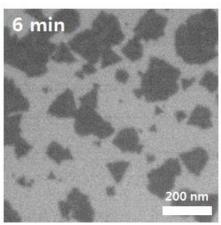


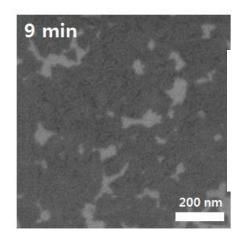
Tube furnace

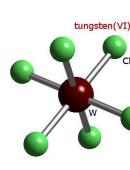
Growth temperature: 700 °C







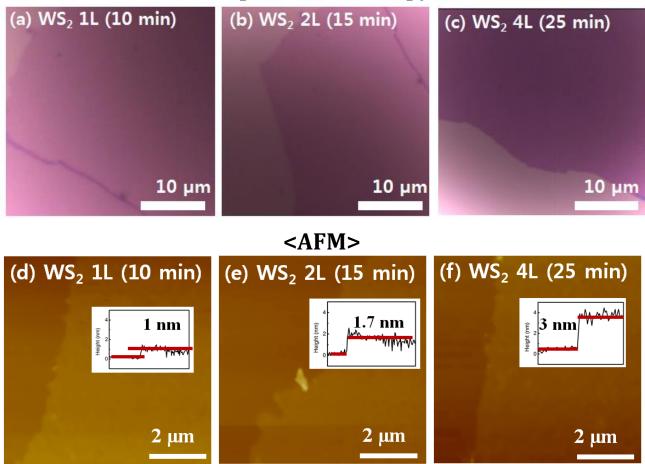




Initial growth of CVD WS₂ → Time dependent lateral growth of WS₂

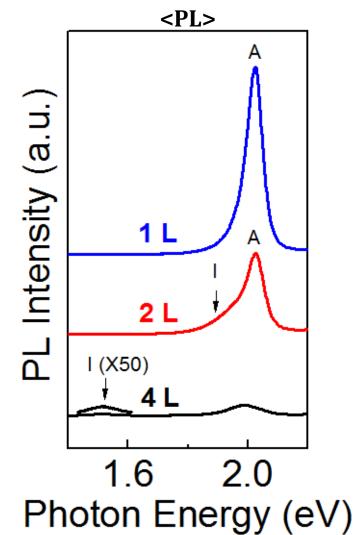
Time dependent Layer Control



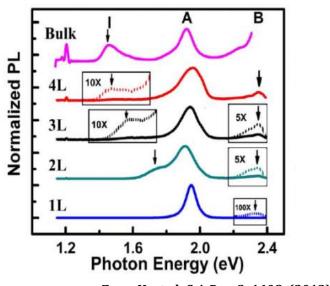


ullet Number of layer dependent on the cycle number of ALD WO $_3$

Optical Property of CVD WS₂



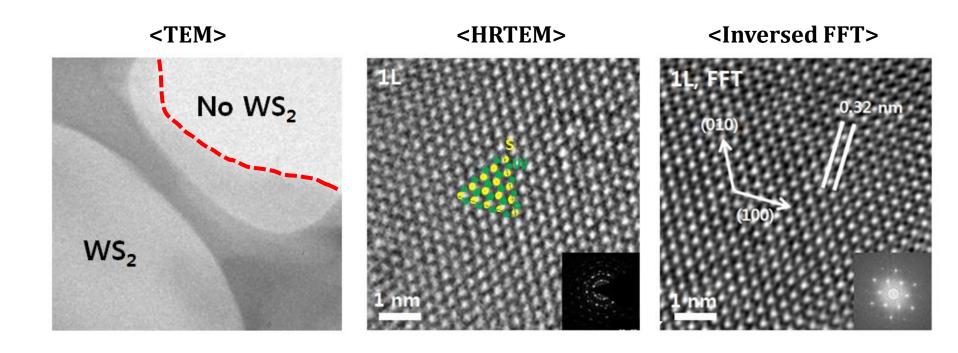
<Electronic structure of WS₂>



Zeng, H. et al, Sci, Rep. 3, 1608, (2013)

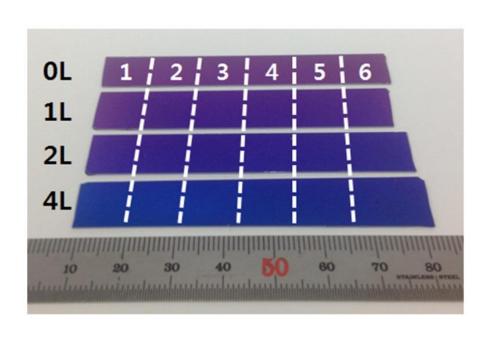
- PL spectra for the 1L, 2L and 4L WS₂ nanosheets
 - → Indirect to direct band gap transition with reducing number of layer
 - → I peak from PL spectrum of 2L and 4L WS₂

Atomic Arrangement of CVD WS₂

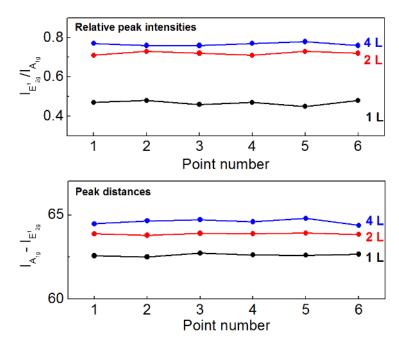


- Low-magnification TEM image for a 1L WS₂ nanosheet on a TEM grid
- HRTEM image of 1L WS₂ nanosheet at a selected region and (inset) the SAED pattern
- Inverse FFT by applying a mask
 - \rightarrow (100) and (110) crystal directions
 - \rightarrow Lattice spacing: 0.26 nm and 0.16 nm for the (100) and (110) planes

Large Area Uniformity of CVD WS₂

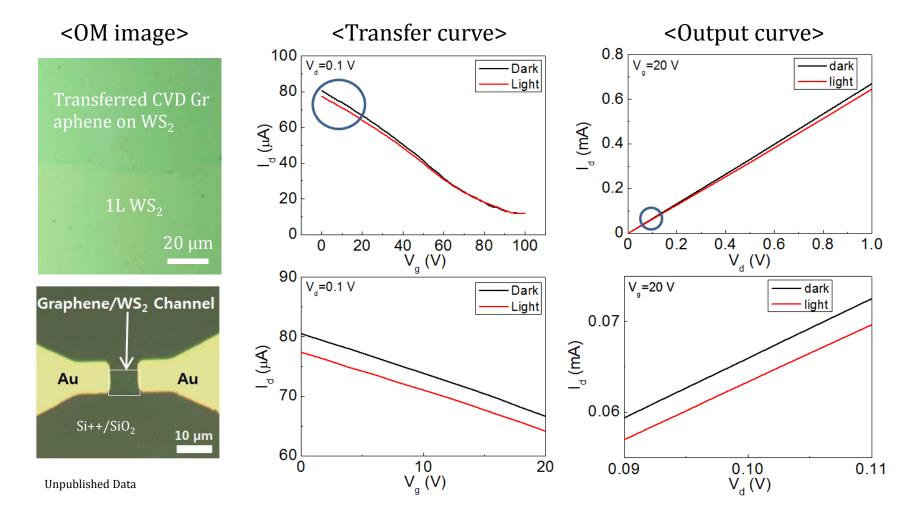


<Raman analysis>



- Color dependency on the number of layers
- Large-area uniformity on 1 cm X 7 cm SiO₂

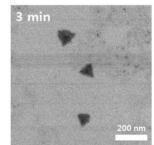
Graphene/WS₂ Photo-Detector

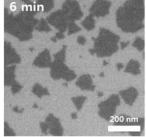


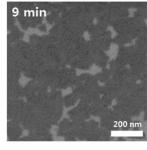
- \triangle Id/Id @ Vg=0 V -> 4% with monochromatic green light (~550 nm) @ 1 W/m²
- Lower than exfoliated few-layer MoS_2 with CVD graphene photo-detector ($\sim 7\% \ @ 0.6 \ W/m^2$)

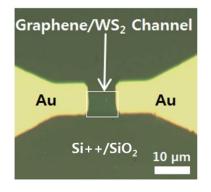
Summary

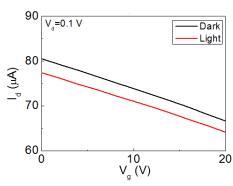
- CVD WS₂ nanosheets are synthesized using gas phase S reactant
- Lateral growth and coalescence of two or more domains are observed
- Number of layer can be controlled by reaction time









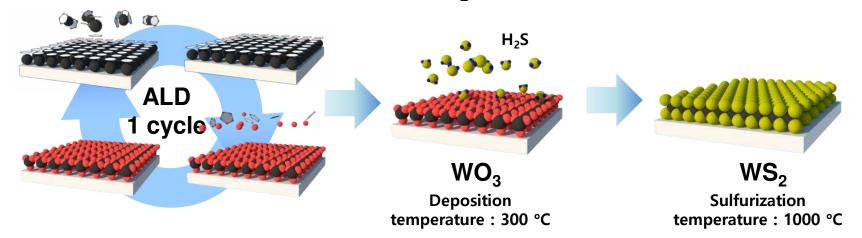


• Graphene/WS₂ hetero-structure shows properties of photo detecting

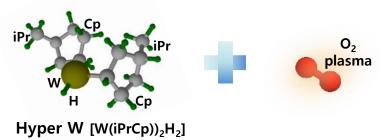
Synthesis of TMDCs nanosheet Based on Atomic Layer Deposition (Metal Oxide Sulfurization)

Synthesis of WS₂ Nanosheets Using ALD

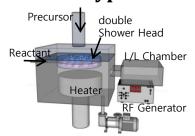
<Pre><Procedure of ALD based WS₂ nanosheets synthesis>



<Precursor and Reactant for ALD WO₃>

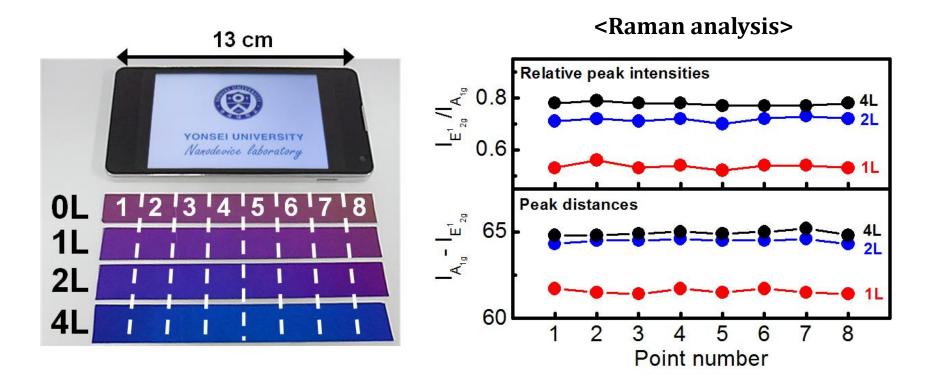


<Shower head type 6 inch ALD>



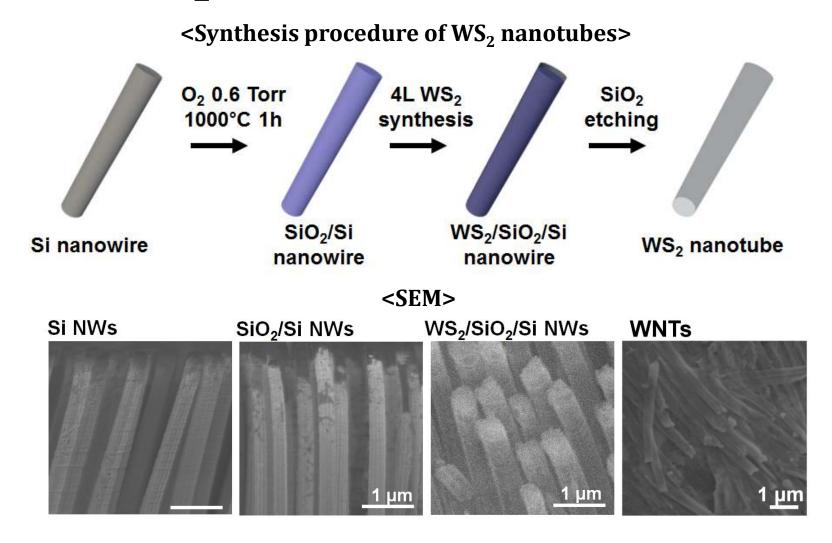
- Hyper W and O₂ plasma as precursor and reactant for ALD WO₃
- Shower head type 6" ALD plasma reactor for ALD WO₃

Wafer-Scale Uniformity of WS₂



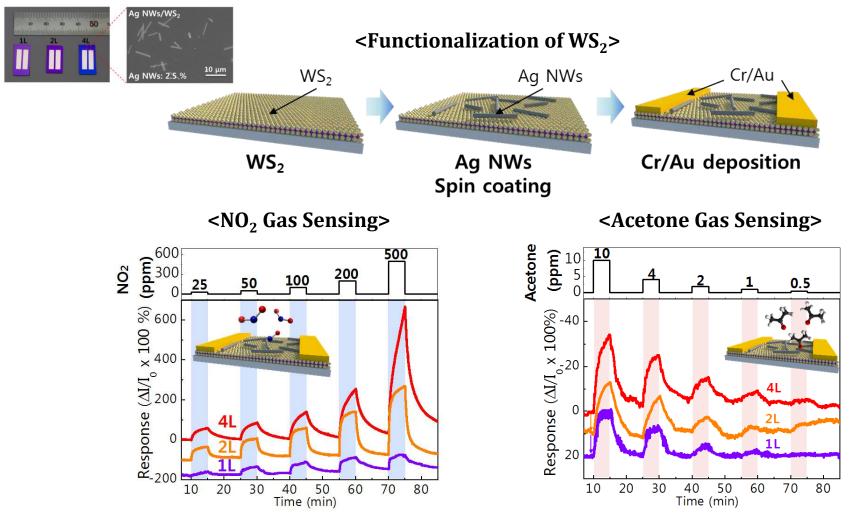
- Large area (approximately 13 cm) 1L, 2L and 4L WS₂ nanosheets
- Relative Raman peak intensities and peak distances of the E^{1}_{2g} and A_{1g} modes for eight measurement points on large area WS₂ nanosheets

WS₂ Nanotubes Fabrication



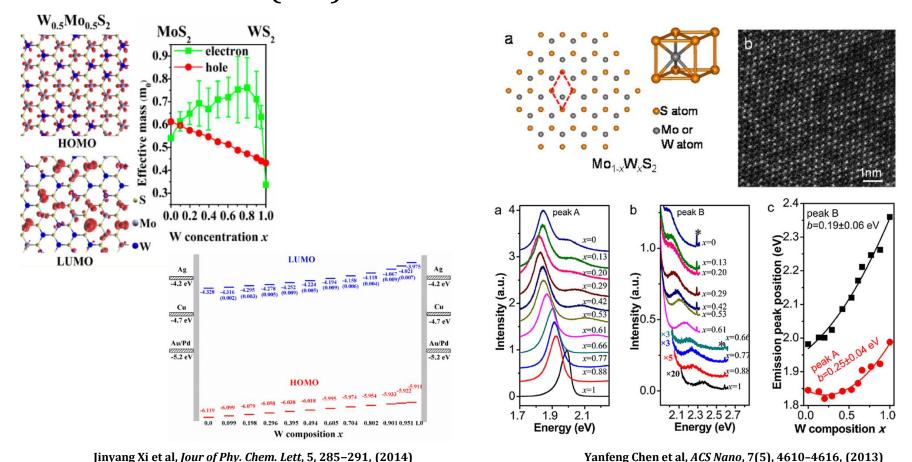
- Conformality of ALD
 - \rightarrow Fabrication of WS₂ nanotubes using ALD based WS₂ proc

Gas Sensing Properties of WS₂



• Highly enhanced response to $NO_2 \rightarrow 12$ times enhanced compared to pristine

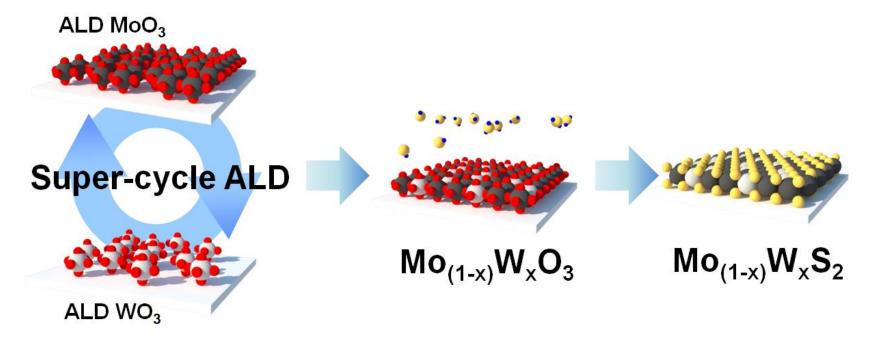
$Mo_{(1-x)}W_xS_2$ Nanosheets



- 2D $Mo_{(1-x)}W_xS_2$ nanosheets
 - → Thermally stable, tunable band gap with control of composition ratio
- No report on synthesis of 2D $Mo_{(1-x)}W_xS_2$ alloy nanosheet

Synthesis of $Mo_{(1-x)}W_xS_2$ Nanosheets

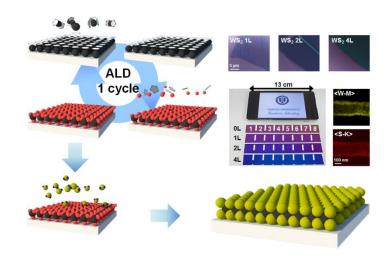
<Synthesis procedure of ALD based $Mo_{(1-x)}W_xS_2$ nanosheets>

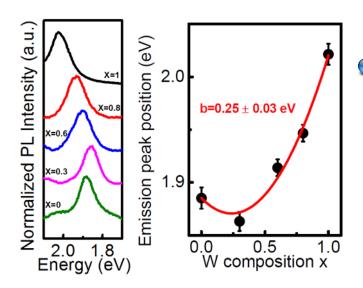


- Sulfurization of $Mo_{(1-x)}W_xO_3$ thin films deposited by super-cycle of PE-ALD
- Depending on the cycle ratio of MoO₃ and WO₃, contents ratio of Mo and W can be controlled

Summary

- ALD based WS₂ nanosheets show
 several advantages of ALD
 - → Atomic scale thickness control,
 - → Wafer-scale uniformity,
 - **→** Conformality

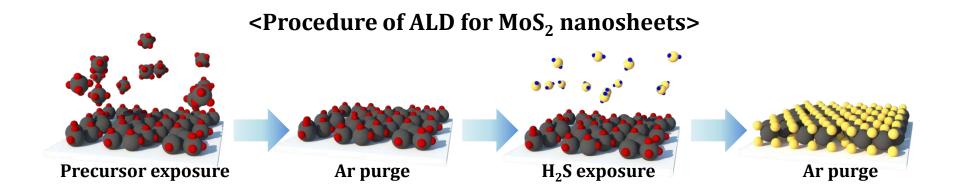




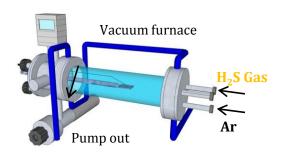
Super-cycle ALD can be possible tuning of band gap of 2D TMDCs nanosheets by synthesis of Mo_(1-x)W_xS₂ alloy and vertical composition-controlled Mo_(1-x)W_xS₂

Synthesis of MoS₂ nanosheet Based on Atomic Layer Deposition (Direct Synthesis)

Synthesis of MoS₂ Nanosheets

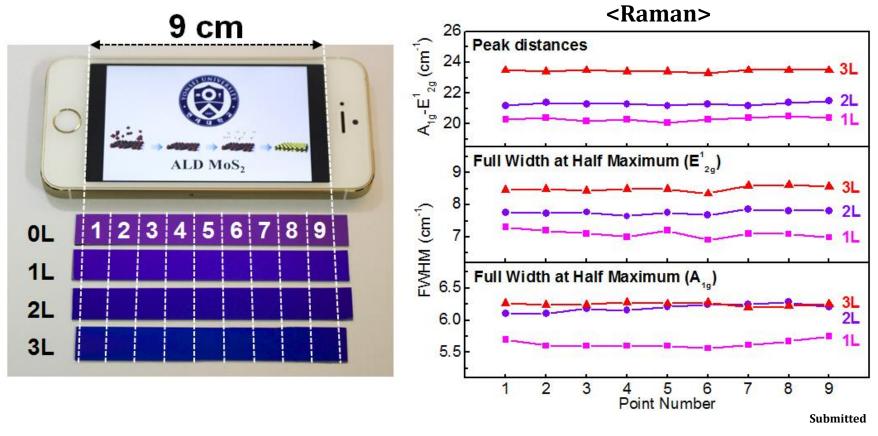


<Equipment for ALD>



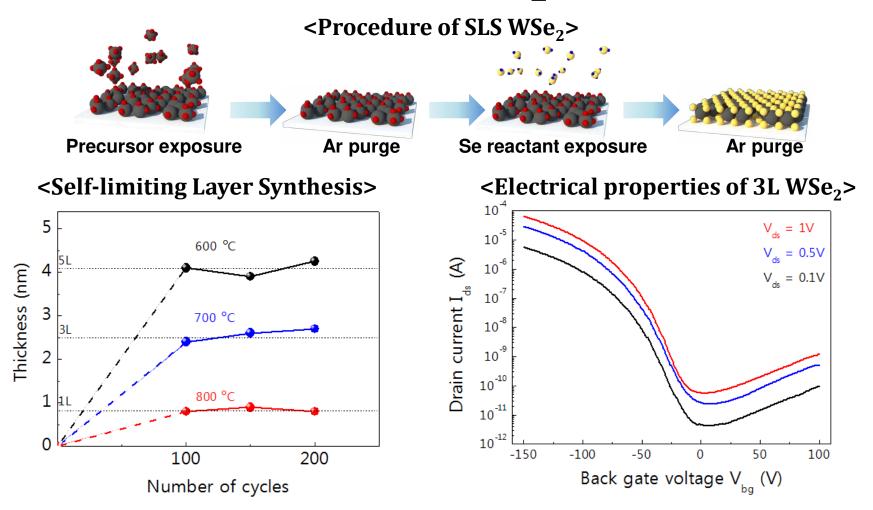
- Gas phase H₂S is employed as the reactant in ALD MoS₂ process
- Tube type furnace ALD reactor for MoS₂

Wafer-Scale Uniformity of MoS₂



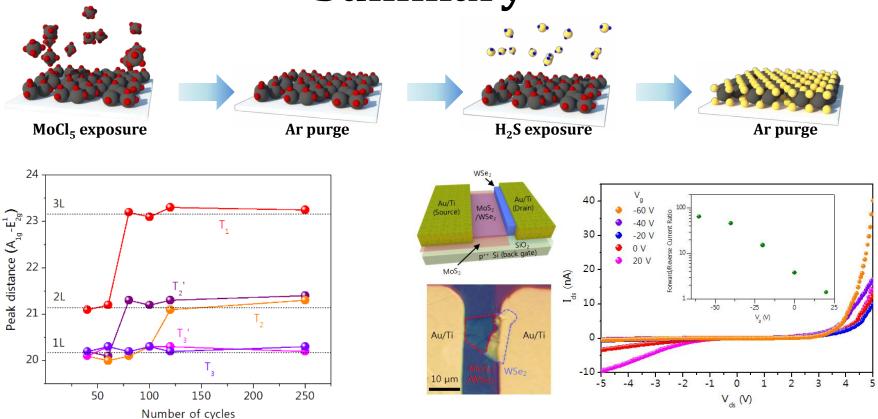
- Large area (approximately 9 cm) 1L, 2L and 3L MoS₂ nanosheets
- Relative Raman peak distances and FWHM for E^{1}_{2g} and A_{1g} modes for nine measurement points on large area MoS_{2} nanosheets
- Results show small variation for the nine points
 - → good thickness uniformity over wafer-scale

SLS WSe₂



- Preserving self-limiting layer synthesis characteristics for WSe₂
 → Universally applicable to synthesize 2D TMDCs
- 3L WSe₂ \rightarrow p-type behavior with mobility = 2.2 cm²/Vs, on/off ratio = 10⁶

Summary



- **■** Synthesis of MoS₂ nanosheet using ALD procedure
 - → Show self-limiting growth behavior (self-limiting layer synthesis, SLS)
- **SLS MoS**₂ shows wafer-scale thickness uniformity and layer controllability
- \bullet SLS MoS₂ valid on WSe₂ surface \rightarrow feasible for 2D TMDCs heterostructure